

SEMI Standards Staff Report

December 12, 2017

SEMI Japan

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SEMI Global 2017/2018 Calendar of Events

Event Name	Event Details
SEMICON Japan 2017	December 13-15, 2017 Tokyo, Japan
SEMICON Korea 2018	January 31 – February 2, 2018 Seoul, South Korea
FPD China 2018	March 14 -16, 2018 Shanghai, China
SEMICON China 2018	March 14 -16, 2018 Shanghai, China
SEMICON Southeast Asia 2018	May 8 - 10, 2018 Kuala Lumpur, Malaysia
SEMICON West 2018	July 10-12, 2018 San Francisco, California

Global Standards Meeting Schedule

<http://www.semi.org/en/standards-events>

- Dec 12-15, 2017
SEMICON Japan Standards Meetings
Tokyo, Japan
- Dec 21, 2017
Automation Technology Japan TC
Chapter Meeting
Tokyo, Japan
- Dec 22, 2017
FPD Metrology Taiwan TC Chapter
Meeting
Hsinchu, Taiwan, Taiwan
- Dec 28, 2017
HB-LED TC Chapter Meeting
Shanghai, China
- Jan 26, 2018
FPD Materials & Components Japan TC
Chapter Meeting
Tokyo, Japan
- Apr 6, 2018
PV and PV Materials Japan TC Chapter Joint
Meeting
Tokyo, Japan
- Apr 9-12, 2018
North America Standards Spring 2018
Meetings
Milpitas, California, USA
- May 26, 2018
PV&PV Materials China TC Chapters joint
Meeting
Shanghai, China
- July 10-12, 2018
SEMICON West 2018
San Francisco, California, USA

SEMICON[®] JAPAN WORLD OF IOT

開催概要

日時： 2017年12月13日（水）～15日（金）

会場： 東京ビッグサイト 東展示棟、会議棟

規模： 750社 1,750小間

延べ来場者： 70,000名

*延べ来場者数は、日毎の入場登録者と出展者を含む延べ人数です。

テーマ



Committee Meetings during SEMICON Japan 2017

■ JRSC (Invitation Only)

- Tuesday, December 12, 15:30-17:30, SEMI Japan office

■ Gases & Facilities joint

- Tuesday, December 12, 13:00-15:00, SEMI Japan office

■ Liquid Chemicals

- Wednesday, December 13, 10:00-12:00, Tokyo Big Sight Conference Tower

■ Physical Interfaces & Carriers

- Wednesday, December 13, 14:00-17:00, Tokyo Big Sight Conference Tower

■ Silicon Wafers

- Thursday, December 14, 14:00-17:00, Tokyo Big Sight Conference Tower

■ Traceability

- Friday, December 15, 10:00-12:00, Tokyo Big Sight Conference Tower

■ Information & Control

- Friday, December 15, 13:00-17:00, Tokyo Big Sight Conference Tower

■ Environmental, Health & Safety,

- Friday, December 15, 13:00-16:00, Tokyo Big Sight Conference Tower

SEMICON Japan 2017 Friendship Party & Award Ceremony

Thursday, December 14, 2017
17:30-19:00

Room 607 Conference Tower Tokyo Big Sight






2017 Critical Dates for SEMI Standards Ballots

Cycle	Ballot Submission Date	Voting Period Starts	Voting Period ends
Cycle 1	January 3	January 17	February 16
Cycle 2	February 3	February 17	March 20
Cycle 3	March 7	March 21	April 20
Cycle 4	April 14	April 25	May 25
Cycle 5	May 12	May 26	June 26
Cycle 6	July 21	August 1	August 31
Cycle 7	August 18	September 1	October 2
Cycle 8	October 13	October 27	November 27
Cycle 9	November 16	November 29	December 29

2018 Critical Dates for SEMI Standards Ballots

Cycle	Ballot Submission Date	Voting Period Starts	Voting Period ends
Cycle 1	January 3	January 16	February 15
Cycle 2	February 7	February 21	March 23
Cycle 3	March 9	March 23	April 23
Cycle 4	April 20	April 30	May 30
Cycle 5	May 11	May 25	June 25
Cycle 6	July 20	August 1	August 31
Cycle 7	August 22	September 5	October 5
Cycle 8	October 12	October 26	November 26
Cycle 9	November 14	November 28	December 28

A&R Ballot Review

A&R Cycle	Result	Notes
January 2017	 A&R_201701	All passed.
May 2017	 A&R_201705	6066A-LI2 and 6068A-LI2 failed. Reason: reapprovals require a separate ballot and cannot be done as a line item ballot.
Jun 2017	 A&R_201706	All passed
August 2017	 A&R_201707	Doc. 6172 (LI1:Correct title and concomitant texts for S14) failed.
September 2017	 A&R_201709	All passed

Recent Balloted Item Failures

- Document 6066A, Line Item 2 (SEMI E130.1 was balloted for reapproval with no changes)
- Document 6068A, Line Item 2 (SEMI E116.1 was balloted for reapproval with no changes)
 - Both documents were failed for the same reason:
 - The Regulations and the Procedure Manual clearly state that a Reapproval Letter Ballot is used for reapproval of a document and that a Line-Item Letter Ballot is a type of revision ballot. Therefore, reapproval cannot be balloted as a line item.
- Document 6172, Line Item 1 (SEMI S14 was balloted for title correction)
 - Failed because the ballot was not accompanied by a Safety Check List, which is required for all Safety Guidelines.

SEMI Standards Publications

Publication Cycle	New	Revised	Reapproved	Withdrawn
December 2016	0	2	0	0
January 2017	1	4	4	0
February 2017	1	9	2	0
March 2017	0	16	11	0
April 2017	0	5	1	0
May 2017	0	4	6	0
June 2017	2*	4	0	0
July 2017	0	1	1	0
August 2017	3	2	1	0
September 2017	0	1	3	0
October 2017	1	12	2	0
November 2017	0	4	0	0

*Including New Auxiliary Document: 1

- Total SEMI Standards in portfolio: **978**
– Includes **214** Inactive Standards

New Standards published in 2017

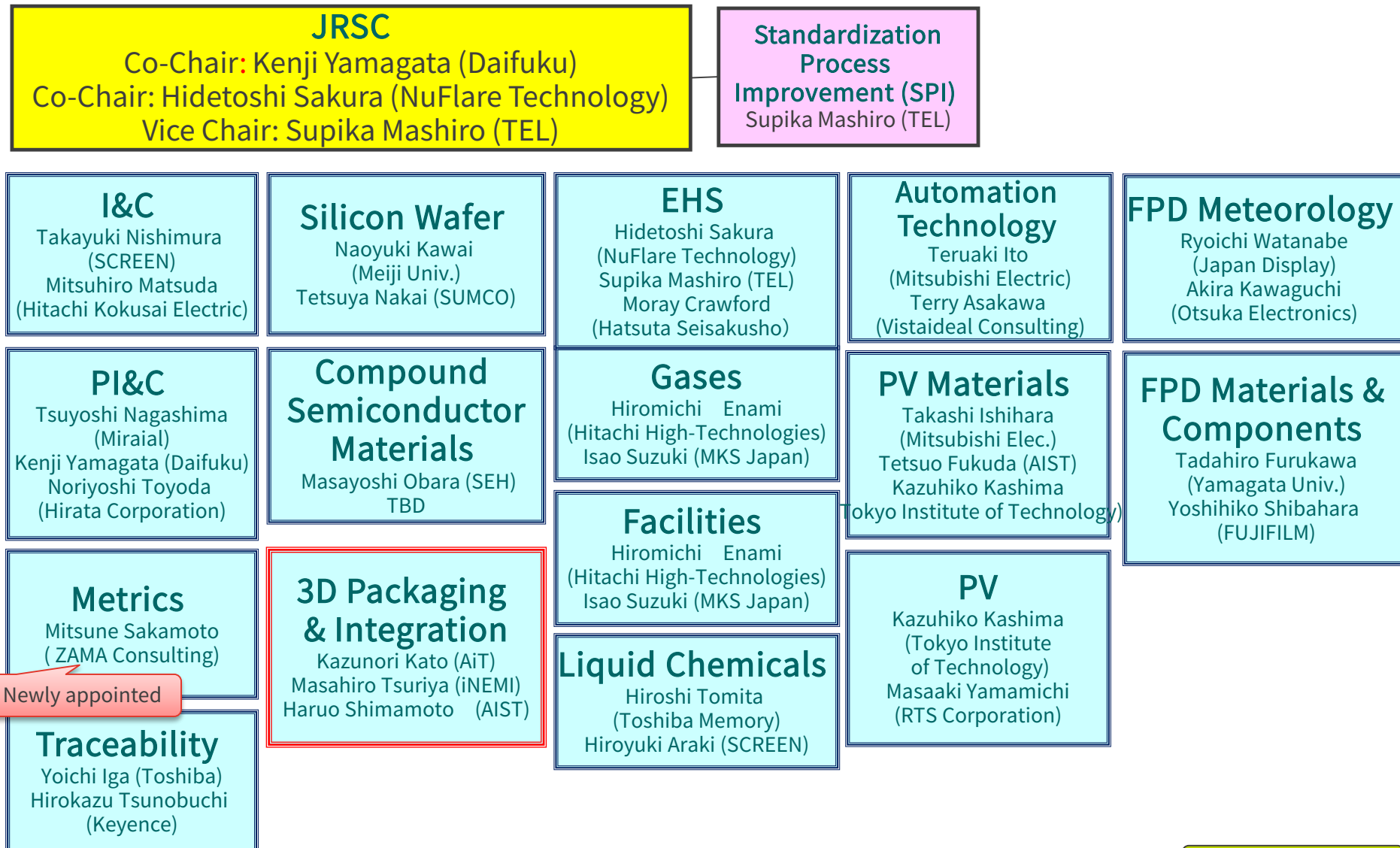
Doc #	Standards #	Title	GTC	Region
5598A	SEMI PV76-0117	Test Method for Durability of Low Light Intensity Organic Photovoltaic (OPV) and Dye-Sensitized Solar Cell (DSSC)	PV	Taiwan
5945	SEMI HB8-0217	Test Method for Determining Orientation of a Sapphire Single Crystal	HB-LED	China
6088	SEMI A1-0617	Specification for Horizontal Communication (HC) Between Equipment for Factory Automation System	AT	Japan
5840	SEMI PV77-0817	Guide for Calibration of Photovoltaic (PV) Module UV Test Chambers	PV	China
5926	SEMI PV78-0817	Test Method for Bending Property of Flexible Thin Film Photovoltaic (PV) Modules	PV	China
6016	SEMI PV79-0817	Test Method for Exposure Durability of Photovoltaic (PV) Cells to Acetic Acid Vapor	PV	Japan
R5596A	SEMI E176-1017	Guide to Assess and Minimize Electromagnetic Interference (EMI) in a Semiconductor Manufacturing Environment	Metrics	North America

JRSCトピックス

- メトリクス委員会
 - 村上達郎氏退任
 - 坂本見恒氏新任
- スタンダード賞とテクニカルコミッティー賞

Takayuki Nishimura	SCREEN Semiconductor Solutions CO., Ltd.		SEMI Japan Standards Award
Masahiro Tsuruya	International Electronics Manufacturing Initiative.		SEMI International Collaboration Award
Haruo Shimamoto	Advanced Industrial Science and Technology		SEMI International Collaboration Award
Mark Takahashi	Asahi Glass Co., LTD.		SEMI International Collaboration Award
Eiji Yoshino	Hitachi High-Technologies Corporation		SEMI International Collaboration Award
Mitsune Sakamoto	ZAMA Consulting		SEMI Japan Special Appreciation Award
Yoshitada Nogami	SK-Electronics CO., LTD.		SEMI Japan Honor Award
Yoshihisa Takasaki	AMS Japan K.K		SEMI Japan Honor Award
Toshio Murakami	Murakami Corporation		SEMI Japan Honor Award
Katsuyoshi Takahashi	Mitsubishi Electric Corporation	Automation Technology	Technical Committee Award
Takafumi Muraoka	Mitsubishi Electric Corporation	Automation Technology	Technical Committee Award
Toshimasa Eguchi	Sumitomo Bakelite Co., Ltd	FPD Materials & Components	Technical Committee Award
Koji Kitajima	Toshiba Memory Corporation	Information & Control	Technical Committee Award
Masahide Hirouchi	IBM Japan, Ltd.	Information & Control	Technical Committee Award
Tadanori Tanahashi	Advanced Industrial Science and Technology	PV Materials	Technical Committee Award

JRSC Organization Chart



SEMI通信（2017年）

テーマ募集中!!

- 2017_01_2016年度SEMIジャパン・スタンダード賞はSUMCOの中井哲弥氏が受賞
- 2017_02_電子部品模造被害の現状とトレーサビリティの国際標準化
- 2017_03_コンポーネントに起因する欠陥を測定するためのベースラインの確立
- 2017_05_SEMI S2 19章「地震保護」改訂
- 2017_06_装置データ収集（EDA）ワーキンググループ
- 2017_07_半導体製造に使用される超純水（UPW）品質管理
- 2017_08_電子顕微鏡グリッドに関する標準化活動開始
- 2017_09_3D Packaging and Integration委員会設立の紹介
- 2017_10_SEMI PV79-0817 酢酸蒸気曝露による太陽電池セル耐久性試験方法の新規発行

Global Staff Assignment - North America

- Kevin Nguyen
 - EHS
 - Micropatterning
 - Silicon Wafer
- Inna Skvortsova
 - Automated Test Equipment
 - Information & Control
 - Liquid Chemicals
 - Metrics
 - Traceability
- Laura Nguyen
 - 3D Packaging & Integration
 - HB-LED
 - Facilities
 - Gases
 - MEMS / NEMS
 - Physical Interfaces & Carriers
 - PV Materials

Global Staff Assignment – Other regions

- China
 - Sophia Huang
 - PV
 - PV Materials
 - HB-LED
- EU
 - James Amano and Kevin Nguyen
 - Automation Technology
 - Compound Semiconductor Materials
 - Gases
 - Liquid Chemicals
 - Information & Control
 - Metrics
 - Physical Interfaces & Carriers
 - PV Materials
 - Silicon Wafer
- Korea
 - Natalie Shim
 - HB-LED
 - FPD Metrology
 - Facilities
 - Information & Control
- Taiwan
 - Dean Chang, CY. Huang
 - 3D Packaging & Integration
 - Automation Technology
 - EHS
 - FPD Metrology
 - Information & Control
 - PV

Staff Contact –Japan, After May 1, 2017

Committee	Staff
PV, PV Materials, Gases, Facilities, Liquid Chemical, I&C, Automation Technology	<i>Mizue Iwamura, Coordinator, Standards & EHS miwamura@semi.org</i>
FPD M&C, FPD Meteorology, PI&C, Metrics, Traceability, EHS, 3D Packaging & Integration	<i>Chie Yanagisawa Manager, Standards & EHS cyanagisawa@semi.org</i>
JRSC (including SPI TF), Compound, Silicon Wafer	<i>Junko Collins Director, Standards & EHS jcollins@semi.org</i>
Others	Staff
Standards Membership	<i>Mizue Iwamura</i>
Standards Products General Information, SEMIViews	<i>Chie Yanagisawa</i>
Other Standards Operation	<i>Junko Collins</i>

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Thank you